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Serial No.:

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Filed:

August 31, 2000

For: CHEMICAL DISPENSING SYSTEM

FOR SEMICONDUCTOR WAFER

PROCESSING

Group Art Unit: 1763

Examiner:

Sylvia R. MacArthur

Atty. Docket:

93-0421.04

Certificate of Mailing (37 C.F.R.§ 1.8)

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail, postage prepaid, in an envelope addressed to: Commissioner for Patents, Washington D.C. 20231, on the date below:

date below:

Date

Signature

PETITION FOR EXTENSION OF TIME UNDER 37 C.F.R. § 1.136(a)

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AUG 13 2001
TC 1700 MAIL ROOP

Commissioner for Patents Washington, D.C. 20231

Dear Sir:

Applicant hereby petitions to extend the period for response to the Office Action mailed <u>January 19, 2001</u> for <u>three (3)</u> months, from <u>April 19, 2001</u> to <u>July 19, 2001</u>.

Accordingly, the requisite fee is \$ 890. The Commissioner is requested to charge this fee, and any additional fee which may be required to Micron Technology, Inc. Deposit Account 13-3092, Order No. 93-0421.04. A duplicate copy of this petition is enclosed.

Respectfully submitted,

Date: 7/19/1

Charles Browtley

Charles B. Brantley, II, Reg. No. 38,086 Micron Technology, Inc. 8000 S. Federal Way Boise, ID 83716-9632 (208) 368-4557

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